A METHOD TO IMPROVE THE FLOW RATE OF IMPRINTING MATERIAL

BACKGROUND OF THE INVENTION

[0035] The present invention is a method of increasing the flow rate of an imprinting layer disposed between a source of radiation and a target to facilitate pattern formation. Infrared radiation is directed toward the target with the imprinting layer substantially transparent to infrared radiation. The target substantially absorbs the infrared radiation to create a thermal energy in the same, and the thermal energy is subsequently transferred to the liquid, causing a temperature rise of the liquid, and thus improving a flow rate of the imprinting layer and reducing the time required to fill the features defined on a mold.